

## Description

A unique combination of Pall's leading edge AresKleen™ purification material combined with Ultramet-L® stainless steel filter media creating the industry's most advanced true point-of-use purifier.

The Gaskleen® ST Purifier assembly is designed to remove contamination from many process gases. Sub ppb level purification is achieved at designed flow rates of up to 5 slpm while providing 0.003 µm filtration.

## Features & Benefits

- Controls and reduces impurities such as O<sub>2</sub>, H<sub>2</sub>O, CO<sub>2</sub>, CO, NMHC, Ni(CO)<sub>4</sub> and Fe(CO)<sub>5</sub>
- One-for-one dimensional replacement of conventional in-line particle filter assemblies
- Assembly hardware is made of 316L stainless steel
- High efficiency diffusion barrier ensures integrity of reactive material during installation
- Superior pressure drop characteristics
- Wide variety of gases purified
- 100% helium leak and pressure tested
- Compact size
- Not orientation sensitive



- Does not generate hazardous waste when used in non-hazardous gas service
- Will not release hydrocarbons
- No detectable metal contribution above background in HCl gas with HCLP material
- No detectable metal contribution above background in HBr gas with HBRP material

## Specifications

<b>Materials</b>	Electropolished 316 L VAR PLUS stainless steel components
<b>Internal Surface Finish</b>	≤ 0.25 µm / 10 µin R <sub>a</sub>
<b>Particle Removal Efficiency Rating</b>	1x10 <sup>9</sup> retention of particles ≥ 0.003 µm up to 5 slpm
<b>Connections</b>	¼" Gasket Seal, Male / Male (VCR <sup>1</sup> compatible)
<b>Maximum Operating Pressure</b>	2200 psig / 152 bar
<b>Maximum operating temperature</b>	100 °C / 212 °F (INP, SIP, FCP, SF6P), 40 °C / 104 °F (GEH4P, OXP, CLXP, HCLP, HBRP, CDAP)

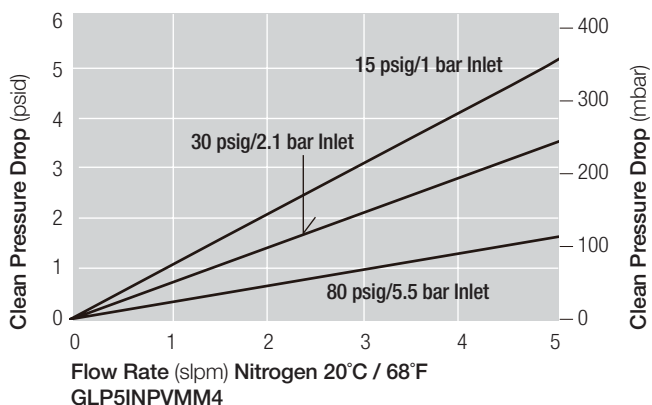
<b>Design Flow Rate</b>	0-5 slpm @ 15 psig / 1 bar Intermittent flow rates up to 10 slpm can be accommodated with reduced lifetime <sup>2</sup>
<b>Packaging</b>	Double bagged Outer bag: aluminized mylar <sup>3</sup> Inner bag: polyethylene End fittings capped with metal seals Product packaged in an argon environment
<b>Nominal Dimensions</b>	Length: 5" / 127 mm Diameter: 1.25" / 31.8 mm
<b>EU pressure Equipment Directive</b>	Assemblies have been evaluated and are CE marked per the European Union's Pressure Equipment Directive 2014/68/EU.

<sup>1</sup> VCR is a trademark of Swagelok Co.

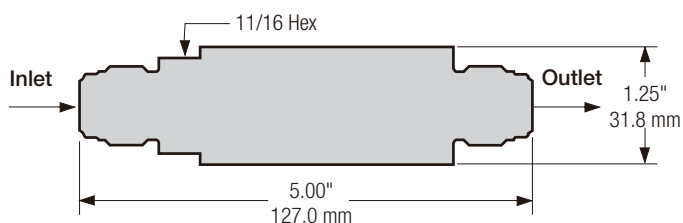
<sup>2</sup> Contact the Pall Microelectronics Group for further information.

<sup>3</sup> Mylar is a registered trademark of Dupont Teijin Films.

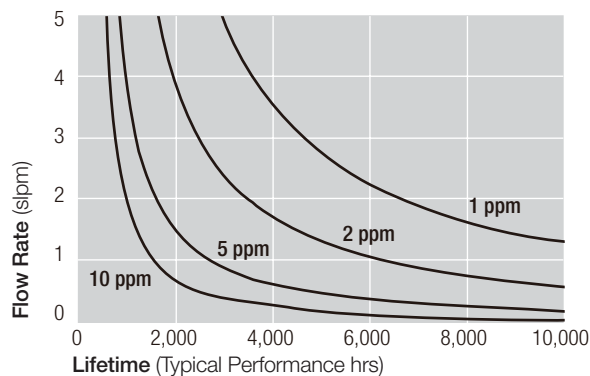
## Pressure Drop vs. Gas Flow Rate



## Nominal Dimensions

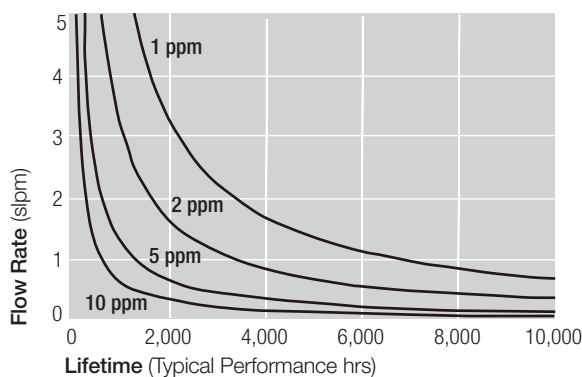


## Lifetime Calculations



**Pall AresKleen Purification Material:** Inert Gas Service  
Gaskleen ST Purifier Assembly, Part # GLP5INPVMM4

**Inlet Pressure:** 30 psig (2.1 bar) Contaminant  
Challenge as H<sub>2</sub>O



**Pall AresKleen Purification Material:** Inert Gas Service  
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**Inlet Pressure:** 30 psig (2.1 bar) Contaminant Challenge as O<sub>2</sub>

## Part Numbers / Ordering Information

Part Number Specifications	Specific Gas	Effluent Purity
GLP5INPVMM4	Inert Gases: Nitrogen, Argon, Helium, Xenon, Krypton, Neon	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub> , CO
GLP5SIPVMM4	Flammable Gases: Silane, Hydrogen, Methane, Ethane, Cyclopropane, Propane, Dimethyl Ether	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub> , CO
	Carbon Monoxide	< 1 ppb H <sub>2</sub> O, O <sub>2</sub> , CO <sub>2</sub> , Ni(CO) <sub>4</sub> , Fe(CO) <sub>5</sub>
GLP5FCPVMM4	Fluoromethane, Difluoromethane, Trifluoromethane, Tetrafluoroethane, Pentafluoroethane, Heptafluoropropane, Carbon Tetrafluoride, Perfluoropropane, Perfluorocyclobutane, Hexafluoroethane	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub>
GLP5GEH4PVMM4	Germane	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub> , CO
GLP5SF6PVMM4	Sulfur Hexafluoride	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub> , CO
GLP5OXPVMM4	Oxygenated Gases: Carbon Dioxide, Oxygen, Nitrous Oxide	< 10 ppb H <sub>2</sub> O
GLP5CLXPVMM4	Chlorinated Gases: Boron Trichloride, Chlorine, Trichlorosilane, Dichlorosilane	< 100 ppb H <sub>2</sub> O
GLP5HCLPVMM4	Hydrogen Chloride	< 15 ppb H <sub>2</sub> O
GLP5HBRPVMM4	Hydrogen Bromide	< 50 ppb H <sub>2</sub> O
GLP5CDAPVMM4	Lithography clean dry air	< 1 ppb H <sub>2</sub> O, < 300 ppt organics (as C <sub>4</sub> ), < 10 ppt acid gases (as SO <sub>2</sub> ), < 15 ppt basic gases (as NH <sub>3</sub> ), < 1 ppt refractory compounds (as HMDSO)

## Technical Information

### Impurity Removal as Tested in Specific Gases

Specific Gas	Impurity Removal Efficiency
Inert Gases: Nitrogen, Argon, Helium, Xenon, Krypton, Neon	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub> , and CO as tested in argon and nitrogen using APIMS analyzer
Flammable Gases: Silane, Hydrogen, Methane, Ethane, Cyclopropane, Propane, Dimethyl Ether	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub> , and CO as tested in argon, nitrogen and hydrogen using APIMS analyzer  < 1 ppb H <sub>2</sub> O as tested in carbon monoxide using trace moisture analyzer  H <sub>2</sub> O and siloxanes removed to trace levels as tested in silane using APIMS
Carbon Monoxide	< 1 ppb Ni(CO) <sub>4</sub> , and < 1 ppb Fe(CO) <sub>5</sub> as tested in carbon monoxide using GC-ECD analyzer
Fluoromethane, Difluoromethane, Trifluoromethane, Tetrafluoroethane, Pentafluoroethane, Heptafluoropropane, Carbon Tetrafluoride, Perfluoropropane, Perfluorocyclobutane, Hexafluoroethane	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub> , and CO as tested in argon and nitrogen using APIMS analyzer  < 1 ppb O <sub>2</sub> as tested in trifluoromethane using trace oxygen analyzer  < 10 ppb H <sub>2</sub> O as tested in trifluoromethane using trace moisture analyzer and FTIR
Germane	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , O <sub>2</sub> , and CO as tested in argon and nitrogen using APIMS analyzer
Sulfur Hexafluoride	< 1 ppb H <sub>2</sub> O, CO <sub>2</sub> , and O <sub>2</sub> as tested in argon using APIMS
Oxygenated Gases: Carbon Dioxide, Oxygen, Nitrous Oxide, Clean Dry Air	< 10 ppb H <sub>2</sub> O < 1 ppb H <sub>2</sub> O, and CO <sub>2</sub> , as tested in argon using APIMS analyzer
Chlorinated Gases: Boron Trichloride, Chlorine, Trichlorosilane, Dichlorosilane	< 100 ppb H <sub>2</sub> O < 1 ppb H <sub>2</sub> O, and CO <sub>2</sub> , as tested in argon using APIMS analyzer
Hydrogen chloride	< 15 ppb H <sub>2</sub> O as tested in hydrogen chloride using CRDS < 1 ppb H <sub>2</sub> O as tested in argon using APIMS analyzer
Hydrogen Bromide	< 50 ppb H <sub>2</sub> O as tested in hydrogen bromide using CRDS < 1 ppb H <sub>2</sub> O as tested in argon using APIMS analyzer
Photolithography clean dry air	< 1 ppb H <sub>2</sub> O as tested in argon using APIMS analyzer < 300 ppt C <sub>4</sub> H <sub>8</sub> as tested in argon using APIMS Analyzer < 10 ppt SO <sub>2</sub> as tested in nitrogen using ion chromatograph < 15 ppt NH <sub>3</sub> as tested in nitrogen using ion chromatograph < 1 ppt HMDSO as tested in argon using APIMS analyzer and baseline subtraction

Unit conversion: 1 bar = 100 kilopascals